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U. S. DEPARTMENT OF COMMERCE

OF

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Complete if Known						
Application Number (10/712,460					
Filing Date	November 13, 2003					
Applicant(s)	Chia-Lin Chen, et al.					
Art Unit	4746 2826					
Examiner Name						
Attorney Docket Number	24061.42 (TSMC2002-1015)					

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Signature	Chuer	Considered	19/15/09

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]					Applicati	ion Number	10/712,460	
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~ 12					Art Unit		9748 2426		
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Examiner Signature	C. Kverhast	Date Considered	10-15-04

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